

ABSTRACT**Method For Manufacturing A Crystalline Layer Of PZT Material, And
Substrate For Epitaxially Growing A Crystalline Layer Of PZT Material**

A process for producing a crystalline layer of PZT material comprising the transfer of a monocrystalline seed layer of SrTiO_3 material to a carrier substrate of silicon material followed by epitaxial growth of the crystalline layer of PZT material.

Figure 2